

Day : Tuesday
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PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = MIEHER

First Name = WALTER

Application#	Patent#	Status	Date Filed	Title	Inventor Name 33
60504093	Not Issued	020	09/19/2003	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
60498524	Not Issued	020	08/27/2003	METHOD AND APPARATUS COMBINING IMAGING AND SCATTEROMETRY FOR OVERLAY METROLOGY	MIEHER, WALTER
60449496	Not Issued	020	02/22/2003	METHOD AND SYSTEM FOR DETERMINING OVERLAY ERRORS BASED ON SCATTEROMETRY SIGNALS ACQUIRED FROM MULTIPLE OVERLAY MEASUREMENT PATTERNS	MIEHER, WALTER DEAN
60441077	Not Issued	020	01/17/2003	METHOD FOR DETERMINING OVERLAY ERROR BY COMPARISON BETWEEN 2 OR MORE MEASURED SCATTEROMETRY SIGNALS	MIEHER, WALTER DEAN
60441048	Not Issued	020	01/17/2003	METHOD FOR PROCESS OPTIMIZATION AND CONTROL BY COMPARISON BETWEEN 2 OR MORE MEASURED SCATTEROMETRY SIGNALS	MIEHER, WALTER DEAN
60440970	Not Issued	020	01/17/2003	METHOD FOR DETERMINING OVERLAY ERROR BY COMPARISON BETWEEN SCATTEROMETRY SIGNALS FROM MULTIPLE OVERLAY MEASUREMENT TARGETS WITH SPECTROSCOPIC IMAGING OR SPECTROSCOPIC SCANNING	MIEHER, WALTER DEAN

APPARATUS					
60431314	Not Issued	020	12/05/2002	METHOD FOR DETERMINING OVERLAY ERROR BY COMPARISON BETWEEN SCATTEROMETRY SIGNALS FROM MULTIPLE OVERLAY MEASUREMENT TARGETS	MIEHER, WALTER
60391290	Not Issued	159	06/24/2002	SPECTROSCOPIC CD METROLOGY FOR SUB-100NM LITHOGRAPHY PROCESS CONTROL	MIEHER, WALTER DEAN
60361837	Not Issued	159	03/04/2002	METHOD FOR DETERMINING LITHOGRAPHIC FOCUS USING MULTIPLE SCATTEROMETRY MEASUREMENTS	MIEHER, WALTER DEAN
60343077	Not Issued	159	12/19/2001	PARAMETRIC PROFILING USING OPTICAL SPECTROSCOPIC SYSTEMS	MIEHER, WALTER
60338204	Not Issued	159	11/09/2001	FOCUS MASKING STRUCTURES, FOCUS PATTERNS AND MEASUREMENTS THEREOF	MIEHER, WALTER DEAN
60301763	Not Issued	159	06/27/2001	OVERLAY MARKS, METHOD OF OVERLAY MARK DESIGNED AND METHODS OF OVERLAY MEASUREMENTS	MIEHER, WALTER DEAN
60301591	Not Issued	159	06/27/2001	OVERLAY MARKS, METHOD OF OVERLAY MARK DESIGNED AND METHODS OF OVERLAY MEASUREMENTS	MIEHER, WALTER DEAN
60301484	Not Issued	159	06/27/2001	OVERLAY MARKS, METHOD OF OVERLAY MARK DESIGNED AND METHODS OF OVERLAY MEASUREMENTS	MIEHER, WALTER DEAN
60301270	Not Issued	159	06/26/2001	METHOD FOR DETERMINING LITHOGRAPHIC FOCUS	MIEHER, WALTER DEAN
60229256	Not Issued	159	08/30/2000	IMAGING TECHNIQUE FOR OVERLAY ALIGNMENT MARKS	MIEHER, WALTER DEAN
10785821	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
10785732	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY	MIEHER, WALTER D.

ERRORS USING SCATTEROMETRY					
<u>10785731</u>	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
<u>10785723</u>	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
<u>10785430</u>	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
<u>10785396</u>	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
<u>10785395</u>	Not Issued	019	02/23/2004	APPARATUS AND METHODS FOR DETECTING OVERLAY ERRORS	MIEHER, WALTER D.
<u>10760149</u>	Not Issued	019	01/17/2004	METHOD FOR PROCESS OPTIMIZATION AND CONTROL BY COMPARISON BETWEEN 2 OR MORE MEASURED SCATTEROMETRY SIGNALS	MIEHER, WALTER
<u>10729838</u>	Not Issued	018	12/05/2003	APPARATUS AND METHOD FOR DETECTING OVERLAY ERRORS USING SCATTEROMETRY	MIEHER, WALTER D.
<u>10327466</u>	Not Issued	020	12/19/2002	PARAMETRIC PROFILING USING OPTICAL SPECTROSCOPIC SYSTEMS	MIEHER, WALTER
<u>10291181</u>	Not Issued	030	11/07/2002	FOCUS MASKING STRUCTURES, FOCUS PATTERNS AND MEASUREMENTS THEREOF	MIEHER, WALTER DEAN
<u>10186324</u>	Not Issued	030	06/26/2002	OVERLAY MARKS, METHODS OF OVERLAY MARK DESIGN AND METHODS OF OVERLAY MEASUREMENTS	MIEHER, WALTER DEAN
<u>10186294</u>	Not Issued	030	06/26/2002	METHOD FOR DETERMINING LITHOGRAPHIC FOCUS AND EXPOSURE	MIEHER, WALTER
<u>10184026</u>	Not	030	06/26/2002	OVERLAY MARKS, METHODS	MIEHER, WALTER

	Issued			OF OVERLAY MARK DESIGN AND METHODS OF OVERLAY MEASUREMENTS	DEAN
10184013	Not Issued	030	06/26/2002	OVERLAY MARKS, METHODS OF OVERLAY MARK DESIGN AND METHODS OF OVERLAY MEASUREMENTS	MIEHER, WALTER DEAN
09894987	Not Issued	030	06/27/2001	OVERLAY MARKS, METHODS OF OVERLAY MARK DESIGN AND METHODS OF OVERLAY MEASUREMENTS	MIEHER, WALTER DEAN
09654318	6486954	150	09/01/2000	OVERLAY ALIGNMENT MEASUREMENT MARK	MIEHER, WALTER DEAN

Inventor Search Completed: No Records to Display.

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